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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/621,031	07/14/2003	James D. Pylant	067810/0303880 PI-018	1179	
7	590 01/14/2005		EXAM	EXAMINER	
PILLSBURY WINTHROP LLP 2550 Hanover Street			HUYNH, LOUIS K		
Palo Alto, CA			ART UNIT	PAPER NUMBER	
·			3721	3721	

DATE MAILED: 01/14/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)			
		10/621,031	PYLANT ET AL.			
	Office Action Summary	Examiner	Art Unit			
		Louis K. Huynh	3721			
	The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply					
THE - External after - If the - If NO - Failu Any I	ORTENED STATUTORY PERIOD FOR REPL MAILING DATE OF THIS COMMUNICATION. Insions of time may be available under the provisions of 37 CFR 1. SIX (6) MONTHS from the mailing date of this communication. In period for reply specified above is less than thirty (30) days, a reply period for reply is specified above, the maximum statutory period re to reply within the set or extended period for reply will, by statuting the process of the mailing of the process of the process of the mailing of the process o		nely filed s will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).			
Status						
1)⊠	Responsive to communication(s) filed on 10 f	November 2004.				
·		s action is non-final.				
3)□	·					
Dispositi	on of Claims					
5)□ 6)⊠ 7)□	4) Claim(s) 1-18 is/are pending in the application. 4a) Of the above claim(s) 1-14 is/are withdrawn from consideration. 5) Claim(s) is/are allowed. 6) Claim(s) 15-18 is/are rejected. 7) Claim(s) is/are objected to. 8) Claim(s) are subject to restriction and/or election requirement.					
Applicati	on Papers					
10)	The specification is objected to by the Examina The drawing(s) filed on is/are: a) accomposite and applicant may not request that any objection to the Replacement drawing sheet(s) including the correct the oath or declaration is objected to by the E	cepted or b) objected to by the E drawing(s) be held in abeyance. See ction is required if the drawing(s) is obj	ected to. See 37 CFR 1.121(d).			
	·	Adminior. Note the attached embe	7.00.001 01 1011111 1 0 102.			
12)[_ / a)[Acknowledgment is made of a claim for foreign All b) Some * c) None of: 1. Certified copies of the priority documen 2. Certified copies of the priority documen 3. Copies of the certified copies of the priority documen application from the International Burea	ts have been received. ts have been received in Application prity documents have been receive nu (PCT Rule 17.2(a)).	on No d in this National Stage			
Attachment	t(s)					
2) 🔯 Notice 3) 🔯 Inform	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (PTO-948) nation Disclosure Statement(s) (PTO-1449 or PTO/SB/08 r No(s)/Mail Date <u>12/1/03 & 11/15/04</u> .	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal Pa				

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DETAILED ACTION

Election/Restrictions

1. Claims 1-14 have been withdrawn from further consideration pursuant to 37 CFR
1.142(b) as being drawn to a nonelected invention, there being no allowable generic or linking claim. Election was made without traverse in the reply filed on 11/10/2004.

Claim Rejections - 35 USC § 103

- 2. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 3. Claims 15-18 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kawada (US 6,119,865) in view of Takeuchi et al. (5,238,876).

Kawada discloses a method of storing a plurality of wafer assembly including the steps of: placing a wafer (4) on an adhesive sheet (3), adhering the adhesive sheet (3) to a frame (2) to form a wafer assembly (1) (col. 2, lines 17-30), sequentially placing and aligning each of a plurality of wafer assemblies (1) into a container (15) along orientation artifacts (16) disposed inside of the container (15) in order to form a stack of wafer assemblies, and covering the container with a cover (17). The method of Kawada meets all of applicant's claimed subject matter but lacks the specific teaching of the wafer frame having at least one alignment artifact disposed thereon for aligning with the orientation artifacts disposed inside the container in order to prevent substantial rotational movement of the wafer assembly within the container.

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However, it is known in the art that a wafer frame is not always in a perfect circular shape as disclosed in the exemplary embodiment of Kawada. Takeuchi discloses a wafer assembly including a ring frame (11), a wafer (1), a tape (10) for holding the wafer (1) to the frame (11); wherein the ring frame (11) has alignment artifacts (straight edges) along the perimeter for mounting onto a chuck (12) in the dicing process such that the alignment artifacts prevent the wafer from rotational movement while the wafer being divided.

Therefore, it would have been obvious to an ordinary skilled person in the art, at the time the invention was made, to have modified the method of Kawada by having replacing the circular wafer frame with one having alignment artifacts, such as one disclosed by Takeuchi, since wafer frame with such alignment artifacts are known for providing alignment in wafer and IC chips manufacturing processes.

Note that the alignment artifacts (straight edges) of the wafer frame of Takeuchi would align with the orientation artifacts (16) of the container (15) of Kawada would prevent substantial rotational movement of the wafer assembly within the container.

Conclusion

- 4. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure has been cited on form PTO-892 along with the applied prior art.
- 5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Louis K. Huynh whose telephone number is (571) 272-4462. The examiner can normally be reached on M-F from 9:30AM to 5:00PM.

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6. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Rinaldi I. Rada can be reached on (571) 272-4467. The fax phone number for the

organization where this application or proceeding is assigned is 703-872-9306.

7. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Louis K. Huynh

PRIMARY EXAMINER

Louis L. Hugh

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December 23, 2004